What is claimed is:

- 1 1. A cutting tool provided with a tool base composed with tungsten carbide-based
- 2 cemented carbide or titanium carbonitride-based Cermet, and a hard coating layer
- 3 provided on the surface of the tool base; wherein the hard coating layer comprises:
- 4 (a) at least one of a Ti compound and a Zr compound layer, which is a lower layer,
- 5 comprising at least one layer of a Ti carbide layer, Ti nitride layer, Ti carbonitride layer, Ti
- 6 oxicarbide layer, Ti oxicarbonitride layer, Zr carbide layer, Zr nitride layer, Zr carbonitride
- 7 layer, Zr oxicarbide layer and Zr oxicarbonitride layer formed by chemical vapor
- 8 deposition, and having an overall mean layer thickness of 0.5-20 μm, and
- 9 (b) an aluminum oxide layer having an α crystal structure in the state of being formed
- by chemical vapor deposition, which is an upper layer, comprising the highest peak in the
- inclination section within a range of 0-10 degrees in the case of emitting an electron beam
- onto individual crystal grains having a hexagonal crystal lattice present within the
- measuring range of the surface polishing plane, measuring the inclination of the (0001)
- crystal plane of the crystal grains relative to the normal of the surface polishing plane
- using a field emission scanning electron microscope, dividing the measured inclinations
- within a range of 0-45 degrees indicated by the individual crystal grains for each pitch of
- 17 0.25 degrees, and preparing a pole plot graph by tabulating the measured inclinations
- 18 present in each section for each section, and having the mean layer thickness is 1-30 um.
- 1 2. A cutting tool according to claim 1, wherein the hard coating layer has an aluminum
- 2 oxide core thin layer containing an aluminum oxide core between the lower layer and the
- 3 upper layer.

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3. A cutting tool according to claim 1, wherein the mean layer thickness of the

- 2 aluminum oxide core thin layer is 20-200 nm.
- 1 4. A method for forming the hard coating layer for a cutting tool according to claim 2,
- 2 comprising:
- forming at least one of the Ti compound and the Zr compound layer;
- 4 forming the aluminum oxide core thin layer on the surface of the at least one of Ti
- 5 compound and the Zr compound layer under conditions of a reaction gas composition,
- 6 in % by volume, of AlCl₃: 3-10%, CO₂: 0.5-3%, C₂H₄: 0.01-0.3% and H₂: remainder, a
- 7 reaction atmosphere temperature of 750-900°C and a reaction atmosphere pressure of 3-13
- 8 kPa; and
- 9 heating the aluminum oxide core thin layer to 1100-1200°C under conditions in
- which the reaction atmosphere is hydrogen and the reaction pressure is 3-13 kPa; and
- forming the aluminum oxide layer having an α crystal structure on the heated
- 12 aluminum oxide core thin layer.